

Noncommutative band offset at α -Cr₂O₃/ α -Fe₂O₃(0001) heterojunctions

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We have measured the valence-band discontinuity at artificially structured, epitaxial heterojunctions of α -Cr₂O₃(0001) and α -Fe₂O₃(0001). Layered film structures of these two materials maintain the in-plane lattice parameter of α -Fe₂O₃(0001). Thus the α -Cr₂O₃(0001) layers are under a 2.4% tensile stress. A partial inward relaxation in α -Cr₂O₃(0001) layers along the *c* axis is also observed, revealing the presence of artificially structured epilayers with a *c/a* ratio of 2.70, compared to 2.78 in bulk α -Cr₂O₃(0001). The valence-band offsets are -0.3 ± 0.1 and $+0.7 \pm 0.1$ eV when the top layer is Fe₂O₃ and Cr₂O₃, respectively. The noncommutativity in the band offset is not due to either anisotropic strain or quantum confinement, but rather appears to be due to a growth-sequence-dependent interface dipole.

I. INTRODUCTION

III–V and II–VI semiconductor heterojunctions have proven to be useful material systems in a wide range of solid-state electronic and optoelectronic devices. In such devices, the valence- and conduction-band discontinuities, or band offsets, at interfaces of dissimilar semiconductors are important parameters in determining such properties as electron-hole pair separation and confinement, leakage current, and gate voltage swing.¹ In comparison, much less is known about analogous interfacial systems involving epitaxial oxide materials. Nevertheless, recent developments point to the importance and potential unique applications afforded by the use of oxides. For instance, epitaxial oxide films have been used as ferroelectric gates in field-effect transistors.² In addition, the magnetic properties of certain transition-metal oxides have given rise to classes of magnetic devices involving spin-polarized electron transport.³ As in the case of traditional compound semiconductors, successful device fabrication and operation depend critically on gaining an in-depth understanding of oxide thin-film and interfacial properties. Critical scientific issues range from adhesion of dissimilar oxide materials to interface electronic structure and its effect on electron transport and scattering. A key aspect of interfacial electronic structure that needs to be understood for epitaxial oxides, but for which we have virtually no experimental results, is the band offset at oxide/oxide heterojunctions.

In this paper, we describe a successful synthesis and band-offset determination for epitaxial α -Fe₂O₃/ α -Cr₂O₃(0001) superlattices, and we point out unusual, but potentially useful, band-offset behavior. These structures were grown by oxygen-plasma-assisted molecular-beam epitaxy (OPA-MBE) on α -Al₂O₃(0001) substrates.⁴ Valence-band offsets were measured by core-level x-ray photoemission using a method pioneered by Kraut *et al.*⁵ In summary, we have found that once an α -Fe₂O₃(0001) epitaxial layer of thickness equal to a few hundred Å or more has been grown, all subsequent α -Cr₂O₃(0001) layers remain under lateral tension and exhibit the same in-plane lattice parameter as α -Fe₂O₃(0001). The out-of-plane lattice parameter contracts slightly to offset the in-plane strain. Thus all heterojunctions formed in this way consist of unstrained

α -Fe₂O₃(0001) and artificially-strained α -Cr₂O₃(0001). In addition, there is a significant noncommutativity in the band offset. This feature may make superlattices of these materials useful for effective spatial separation of electrons and holes due to the potential gradient that is expected to develop over a few periods of the superlattice.

II. EXPERIMENT

The system used to conduct this work is described in detail elsewhere.⁴ In brief, the system consists of three coupled UHV chambers that perform OPA-MBE, atomic force microscopy, (AFM), scanning tunneling microscopy, (STM), and x-ray photoelectron spectroscopy (XPS) diffraction (XPD). Specimens are readily transferred between these chambers, and the loadlock under UHV conditions by means of a transfer tube.

Substrates of α -Al₂O₃(0001) were initially cleaned by ultrasonic washing in acetone and isopropanol prior to insertion into UHV. They were then further cleaned in the MBE chamber by exposure to an oxygen plasma beam at a chamber pressure of 2×10^{-5} torr and a plasma power level of 250 W, with the sample at room temperature. All epitaxial films were grown at a substrate temperature of ~ 500 °C using a metal evaporation rate of ~ 0.1 Å/sec, an oxygen partial pressure of 2×10^{-5} torr, and an electron cyclotron resonance plasma power level of 250 W.

The in-plane lattice parameters and (00) beam intensities of the growing film surfaces were monitored in real time using reflection high-energy electron diffraction (RHEED) in the MBE chamber. Following cooldown and RHEED measurements made with the film surfaces near room temperature, the specimens were transferred to the photoemission chamber for core- and valence-level XPS using monochromatic Al *K*α x rays. An electron flood gun was required for all photoemission measurements due to the insulating nature of these materials. All deep core-level spectra were shifted so the O 1*s* peak fell at 530.0 eV. Likewise, all shallow core-level and valence-band spectra were shifted to place the O 2*s* peak at 23.0 eV. However, these choices are arbitrary, and did not affect the subsequent analysis in any way, since the

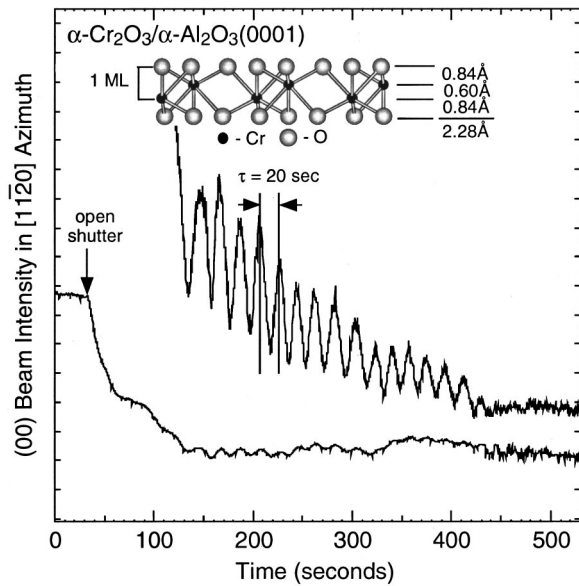


FIG. 1. RHEED (00) beam intensity oscillations during the OPA-MBE growth of α -Cr₂O₃ on α -Al₂O₃(0001). The 30-keV beam was aligned parallel to $[1\bar{1}\bar{2}0]$. The nominal metal evaporation rate, as measured by a QCO adjacent to the substrate, was ~ 0.1 Å/sec.

band-offset determination depends on binding energy differences rather than absolute values.⁵

The thicknesses of α -Fe₂O₃ films were determined by Rutherford backscattering (RBS) conducted *ex situ* in a dedicated RBS chamber.⁶ Thicknesses for α -Cr₂O₃ films were determined by RHEED intensity oscillations, as discussed below. The total film thickness of α -Cr₂O₃/ α -Fe₂O₃ superlattice structures determined absolutely by TEM were in agreement with those estimated from RBS and RHEED oscillations to within ~ 10 – 12 %. A JEOL 2010 microscope was used for all TEM measurements.

III. RESULTS

A. Film and interface structure

The in-plane lattice parameters (a) for bulk α -Al₂O₃(0001), α -Cr₂O₃(0001) and α -Fe₂O₃(0001) are 4.76, 4.92, and 5.03 Å, respectively. The associated out-of-plane lattice parameters (c) are 12.99, 13.7, and 13.7 Å, respectively. All three materials exhibit a corundumlike crystal structure. The in-plane lattice mismatch, defined as $(a_{\text{film}} - a_{\text{sub}})/a_{\text{sub}}$, is +3.36 and +5.80% for α -Cr₂O₃ and α -Fe₂O₃ on α -Al₂O₃(0001), respectively. Previous work has shown that the large lattice mismatch for α -Fe₂O₃ on α -Al₂O₃(0001) results in three-dimensional island growth under the best of conditions.^{7,8} The resulting epitaxial nanocrystals uniformly orient in the same way on the substrate, and eventually agglomerate after several hundred to ~ 1000 Å. In contrast, there is to the best of our knowledge nothing in the literature about the OPA-MBE growth of α -Cr₂O₃ on α -Al₂O₃(0001). The smaller lattice mismatch improves prospects for a more laminar growth mode.

In Fig. 1 we show a typical (00) beam RHEED intensity vs time curve for α -Cr₂O₃ growth on α -Al₂O₃(0001) with the primary beam aligned parallel to $[11\bar{2}0]$. Nearly identical

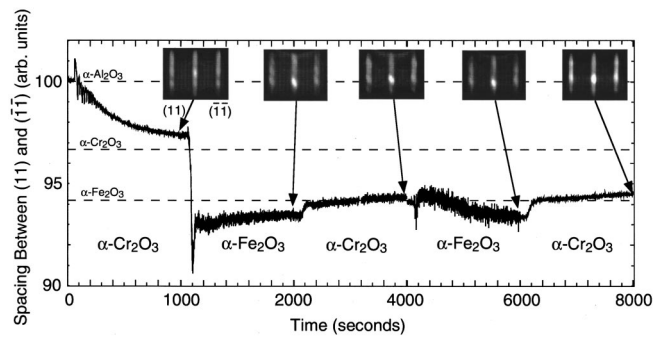


FIG. 2. RHEED streak spacing during α -Cr₂O₃/ α -Fe₂O₃ superlattice growth on α -Al₂O₃(0001). The 30-keV beam was aligned parallel to $[1\bar{1}\bar{0}0]$. The metal evaporation rate was ~ 0.1 Å/sec, as measured by a QCO adjacent to the substrate.

oscillations were measured when the primary beam was aligned along $[1\bar{1}\bar{0}0]$. The Cr shutter was opened at $t = 35$ sec. The intensity dropped monotonically during the first ~ 40 sec of growth, and then exhibited weak, nonperiodic oscillations for the next ~ 60 sec. The intensity then underwent weak, periodic oscillations for the next ~ 310 sec that gradually damped to zero amplitude. This behavior suggests that nominal layer-by-layer growth occurred during the periodic oscillatory portion, from 135 to 445 sec. The period was ~ 20 sec during this portion of the growth, yielding ~ 20 sec as the characteristic time for the completion of full monolayers of α -Cr₂O₃ in the corundum structure.⁹ Thus ~ 16 complete monolayers grew in a quasi-layer-by-layer fashion. However, the beam intensity at all times during these oscillations remained well below that of the starting substrate, indicating that the film surface has a much higher step density than the substrate surface. The in-plane lattice parameter steadily increased from the value of the substrate to that of α -Cr₂O₃ throughout the growth, as seen in Fig. 2. Here we plot the streak spacing in pixels between the (11) and $(\bar{1}\bar{1})$ RHEED beams, normalized to a value of 100 for α -Al₂O₃(0001), for several layers of α -Cr₂O₃ and α -Fe₂O₃ in a superlattice structure. The primary beam was aligned along $[1\bar{1}\bar{0}0]$. The streak spacings expected for bulk α -Cr₂O₃ and α -Fe₂O₃ are shown as dashed lines, as is that for the substrate. The cessation of RHEED oscillations after 16 ML may signal a transition from layer-by-layer to step-flow growth. Inspection of Fig. 2 reveals that the first α -Cr₂O₃ film is still in the process of relaxing when the intensity oscillations cease.

The brief oscillatory period shown in Fig. 1 allows the Cr₂O₃ growth rate to be calibrated at ~ 0.050 ML/sec, which is equivalent to a α -Cr₂O₃(0001) growth rate of ~ 0.12 Å/sec. Here 1 ML of α -Cr₂O₃(0001) is defined as two layers of Cr, and one close-packed O layer in the corundum structure. Each Cr layer has one-third the number of atoms found in the close-packed O layer. This basic structural ML unit is shown in Fig. 1. Since the growth is carried out under oxygen-rich conditions, the growth rate is determined by the rate at which Cr cations are delivered to the substrate. The number density of Cr cations in the α -Cr₂O₃(0001) structure is such that 1.0 Å of Cr metal will result in 1.01 ML of α -Cr₂O₃(0001), which will add 2.3 Å of film thickness. Based on the period of the RHEED oscillations shown in

Fig. 1, the thickness of the first α -Cr₂O₃ film is estimated to be 120 Å. No sustained RHEED intensity oscillations were observed during α -Fe₂O₃ film growth at any time, as is the case for α -Fe₂O₃ grown directly on α -Al₂O₃(0001).^{7,8}

Returning now to Fig. 2, a RHEED pattern of the zeroth-order Laue zone obtained after closing the Cr shutter, but before opening the Fe shutter, after the completion of the first α -Cr₂O₃ film, is shown in Fig. 2. The streaky character, which was observed throughout the growth, indicates that the film surface is reasonably flat. The in-plane lattice parameter had not yet fully converged to the value of bulk α -Cr₂O₃, although it was quite close by the end of the growth. Following a very large apparent increase ($\sim 7\%$) at the onset, the in-plane lattice parameter rapidly converged to a value very close to that of bulk α -Fe₂O₃ upon opening the Fe shutter and initiating the first α -Fe₂O₃ layer growth. The apparent increase in lattice parameter to a value well above that of α -Fe₂O₃ has been seen before for growth directly on α -Al₂O₃(0001), and has been ascribed to the formation of a highly strained, buckled wetting layer that forms in response to the 5.8% lattice mismatch.^{7,8} Presumably, a similar phenomenon occurs here. The RHEED pattern taken at completion of the first α -Fe₂O₃ film reveals that the surface remains reasonably smooth, although some transmission is evident based on the intensity modulation along the streaks, betraying some roughening at the film surface. The thickness of each α -Fe₂O₃ layer was determined to be ~ 140 Å based on a calibration of the QCO growth rate with RBS measurements for pure α -Fe₂O₃(0001) films grown on α -Al₂O₃(0001) substrates.

Very curious behavior of the in-plane lattice parameter was then observed upon growth of the second α -Cr₂O₃ layer, which was the *first* one to be grown on α -Fe₂O₃. The α -Cr₂O₃ lattice parameter remained fixed at the value expected for bulk α -Fe₂O₃. Thus the α -Cr₂O₃ layer was found to be in lateral tension on α -Fe₂O₃. This behavior was also observed after the completion of all other α -Cr₂O₃ layers in several superlattice structures, including some that were up to 600 Å thick. In addition, the same result was obtained from RHEED patterns for superlattice structures in which the specimen was allowed to cool to near room temperature after the completion of each layer. A series of such streak spacing measurements is shown in Fig. 3. These are more accurate than those obtained when the specimen was hot and the Cr and Fe electron-beam evaporators were running because of electromagnetic interference (EMI) between the various filaments and the RHEED beam. Such EMI causes slight distortions in the patterns, as can be seen by inspection of Fig. 2, producing inaccuracies in the measured streak spacings. These inaccuracies may explain, for instance, why the apparent in-plane lattice parameters of α -Fe₂O₃ films shown in Fig. 2 deviate slightly from that of bulk α -Fe₂O₃. However, no such deviations were seen when the sample was cool. As seen in Fig. 3, the streak spacing for thick and thin films of both α -Fe₂O₃ and α -Cr₂O₃ are quantitatively equal, and the value is $5.9 \pm 0.3\%$ smaller than that of α -Al₂O₃(0001). This value is within experimental error of the in-plane lattice mismatch between α -Fe₂O₃(0001) and α -Al₂O₃(0001), indicating that Fe₂O₃ films are relaxed, whereas those of Cr₂O₃ are pseudomorphic on the Fe₂O₃ lattice, even for α -Cr₂O₃ film

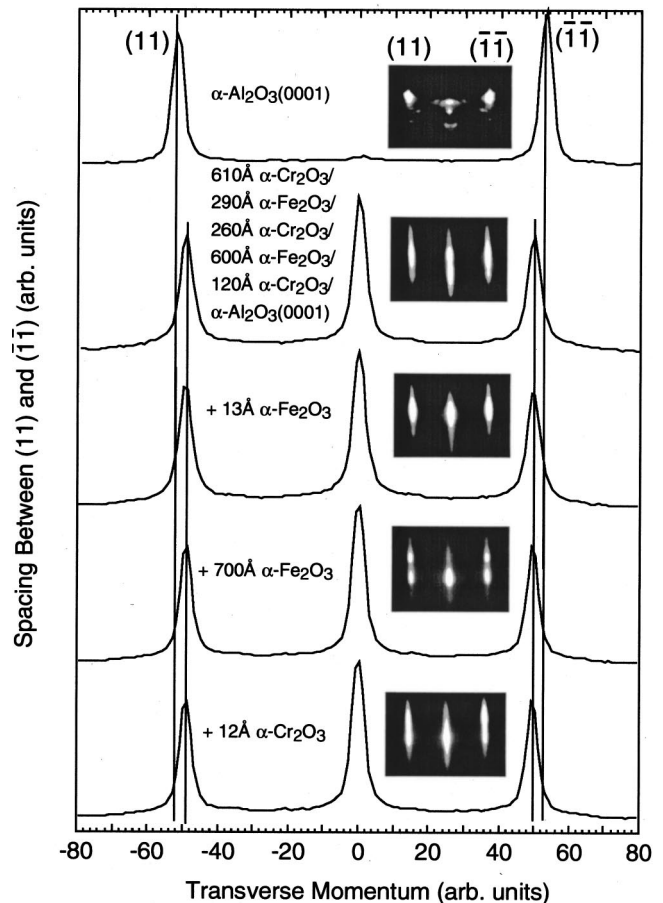


FIG. 3. RHEED patterns and transverse line scans, with the 30-keV primary beam aligned along $[1\bar{1}00]$, for an α -Al₂O₃(0001) substrate, and for thick and thin epitaxial films of α -Fe₂O₃(0001) and α -Cr₂O₃(0001).

thicknesses of several hundred Å. This surprising result may be related to the fact that the out-of-plane lattice parameter c may contract in order to compensate for the in-plane tensile strain. In order to test this hypothesis, we turn to TEM and related selected-area diffraction patterns, which are shown in Figs. 4 and 5.

Figures 4(a) and 4(b) show low- and high-resolution bright-field TEM micrographs of a superlattice structure obtained in cross section. The nominal layer thicknesses, obtained by *ex situ* RBS and RHEED oscillations for Fe₂O₃ and Cr₂O₃ layers, respectively, were 740-Å α -Cr₂O₃/140-Å α -Fe₂O₃/120-Å α -Cr₂O₃/140-Å α -Fe₂O₃/120-Å α -Cr₂O₃/ α -Al₂O₃(0001). The total thickness nominal thickness, 1260 Å, is in reasonable agreement with the thickness measured directly by TEM, 1450 Å. The individual interface locations cannot be unambiguously determined, with the exception of those at the bottom (α -Cr₂O₃/ α -Al₂O₃) and top (epoxy/ α -Cr₂O₃) of the stack. The approximate locations are indicated with lines in Fig. 4(a). However, it is clear from the low-resolution image that the dislocation density is high in the first α -Cr₂O₃ layer. The high-resolution lattice image shown in Fig. 4(b) reveals an individual misfit dislocation. The high dislocation density in the first α -Cr₂O₃ layer is presumably due to the large lattice mismatch between α -Cr₂O₃ and α -Al₂O₃. In Fig. 5 we show a selected area diffraction pattern obtained for the entire film stack and a

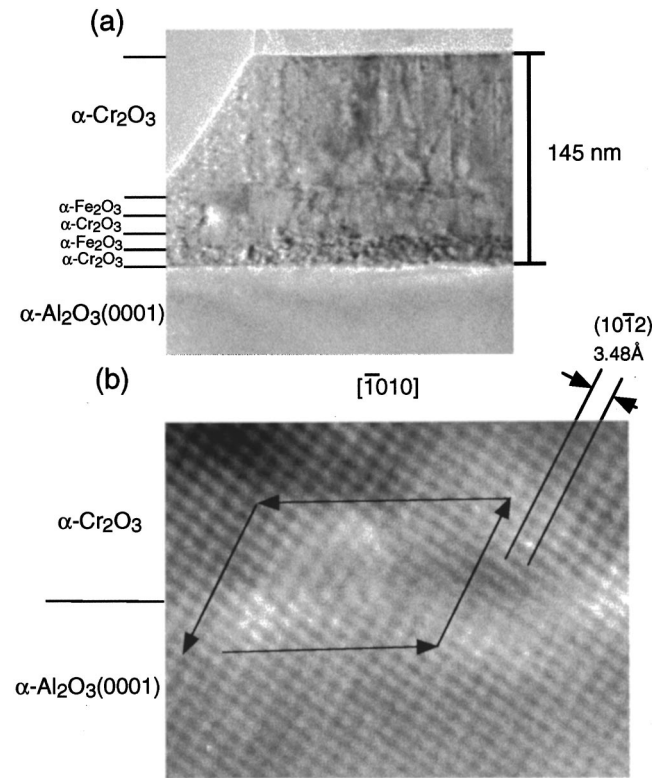


FIG. 4. (a) Low-resolution and (b) high-resolution bright-field TEM micrographs of a α - $\text{Cr}_2\text{O}_3/\alpha$ - Fe_2O_3 superlattice grown on α - $\text{Al}_2\text{O}_3(0001)$. The 200-keV beam was aligned parallel to $[10\bar{1}0]$.

portion of the substrate. The crystal orientation was the same as that shown in Fig. 4. Examination of the less intense diffraction beams reveals the presence of three individual beams distributed along the growth direction. A line scan across the (0012) beam is shown at the bottom of Fig. 5. The largest peak is the (0012) reflection from the substrate, for which c is 13.0 Å. Likewise, (0012) reflections are also seen corresponding to the relaxed Fe_2O_3 layers and the distorted Cr_2O_3 layers. The peak positions reveal that the strained Cr_2O_3 layers possess a c value of 13.5 Å. Thus these layers relax inwardly by ~ 0.2 Å in the c direction in order to partially compensate for the tensile stress created by remaining pseudomorphic on Fe_2O_3 .

In Fig. 6 we show Fe $2p$, Cr $2p$, and O $1s$ core-level spectra obtained for thick (several hundred Å) films of Fe_2O_3 (a) and Cr_2O_3 (b), and an ~ 12 -Å-thick film of Cr_2O_3 on Fe_2O_3 (c). Spectra for a thin film of Fe_2O_3 on Cr_2O_3 are not shown, because these spectra are the same as those shown in Fig. 6(c). The spectra for the thin film, which probe the interfacial region, are the same as those for the thick films, which are representative of the pure materials. The Fe and Cr $2p$ spectra are strongly affected by shake-up, phonon broadening, and multiplet splitting in the final state.¹⁰ Such well-resolved spectra are useful fingerprints of the local electronic and magnetic environment of the Fe(III) and Cr(III) cations in the oxide lattice. The fact that the thin-film spectra are the same as those of the pure materials reveals that there is no detectable reduction of either Fe or Cr at the interface, indicating no oxygen vacancies. In addition, the O $1s$ line shapes and peak widths are virtually indistinguishable for the three specimens, indicating that the oxygen sublattice is unper-

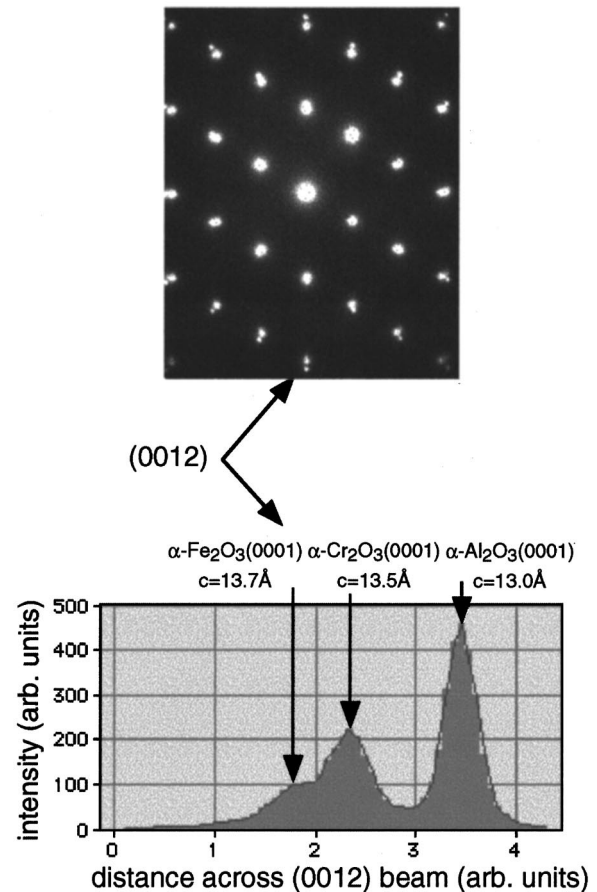


FIG. 5. TEM-selected area diffraction pattern for the α - $\text{Cr}_2\text{O}_3/\alpha$ - Fe_2O_3 superlattice grown on α - $\text{Al}_2\text{O}_3(0001)$, described in conjunction with Fig. 4, along with an intensity profile along the (0012) diffraction beam.

turbed across the interface. Extensive intermixing, leading to substrate atom outdiffusion to the free surface measurable by XPS does not occur with these materials. Cr (Fe) was never detected by XPS in the near-surface region of Fe_2O_3 (Cr_2O_3) films of any thickness great enough to completely attenuate photoemission from the underlying layer. Nevertheless, limited intermixing at individual interfaces probably does occur, since α - Fe_2O_3 and α - Cr_2O_3 form a solid solution over the complete range of composition.¹¹ Indeed, some Fe was detected by secondary ion mass spectrometry at the surface of a terminal 120-Å-thick layer of α - Cr_2O_3 , indicating limited Fe outdiffusion. However, Cr (Fe) $2p$ intensity attenuation upon growth of Fe_2O_3 (Cr_2O_3) thin films is consistent with reasonably abrupt interfaces.

B. Band-offset determination

In Fig. 7 we show the shallow Fe and Cr $3p$ core levels, along with the valence bands, from which the band offsets were determined. Determining the core-level binding energies in a consistent and reproducible way was made somewhat difficult by multiplet splitting, which complicates the line shape. Nevertheless, taking the difference between these core-level binding energies and the leading edge of the valence bands, as shown in the inset, for surfaces of the pure materials leads to values of $\Delta E_{\text{Me } 3p-\text{VB}}$ of 42.62 ± 0.03 and

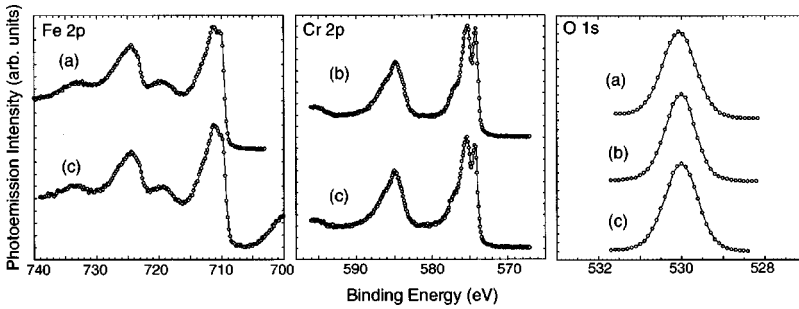


FIG. 6. Fe 2*p*, Cr 2*p*, and O 1*s* core-level photoemission spectra obtained at normal emission for (a) unstrained α -Fe₂O₃(0001), (b) strained α -Cr₂O₃(0001), and, (c) \sim 12-Å-thick film of α -Cr₂O₃(0001) on α -Fe₂O₃(0001).

54.26 ± 0.09 eV for α -Cr₂O₃(0001) and α -Fe₂O₃(0001), respectively. Likewise, differences in core-level binding energies, $\Delta E_{\text{Fe } 3p - \text{Cr } 3p}$, for the thin films were 11.99 ± 0.09 and 12.34 ± 0.08 eV for Fe₂O₃ on Cr₂O₃ and Cr₂O₃ on Fe₂O₃, respectively. Each of these numbers is the average value from four separate film growths, and the uncertainties are standard deviations. The valence-band offsets are then determined to be -0.3 ± 0.1 and $+0.7 \pm 0.1$ eV for Fe₂O₃ on Cr₂O₃ and Cr₂O₃ on Fe₂O₃, respectively. Here our sign convention is that the band offset is negative (positive) if the overlayer band is bound more strongly (weakly) than the underlayer band. We emphasize that the strain configuration is unchanged as a result of inverting the growth sequence; the α -Cr₂O₃ layers are under a 2.4% tensile stress, whereas the α -Fe₂O₃ layers are relaxed, as discussed in Sec. III A. Therefore, strain is not a factor in the observed band-offset

noncommutativity. In fact, the valence-band offset at the first α -Fe₂O₃/ α -Cr₂O₃ interface grown on a given α -Al₂O₃(0001) substrate, for which both layers are relaxed (see the left side of Fig. 2), is also -0.3 ± 0.1 eV, revealing that strain apparently does not affect the band offset for this oxide/oxide heterojunction in any measurable way.

The band offsets are shown in an energy-level diagram in Fig. 8(a). Here we have neglected band bending, which is likely to be negligible compared to the film thicknesses used because the films are undoped. Using the bulk band gaps of Fe₂O₃¹² and Cr₂O₃,¹³ we can also estimate the conduction-band offsets, as shown in Fig. 8(a). It is likely that the band gap of strained, epitaxial α -Cr₂O₃(0001) differs from that of the unstrained bulk material. In order to determine if such a difference exists, we attempted to measure the band gap of

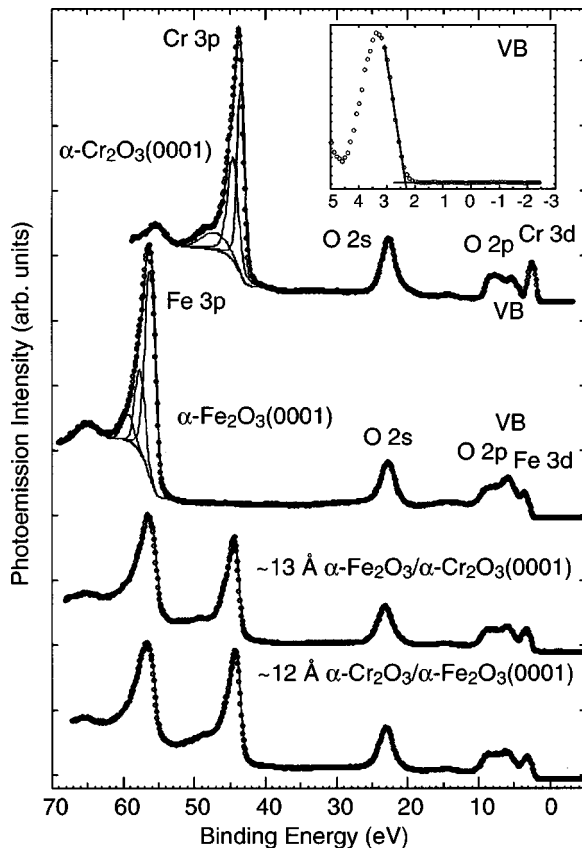


FIG. 7. Fe 3*p*, Cr 3*p*, O 2*s*, and valence band (VB) spectra for strained α -Cr₂O₃(0001), unstrained α -Fe₂O₃(0001), and α -Fe₂O₃(0001)/ α -Cr₂O₃(0001) and α -Cr₂O₃(0001)/ α -Fe₂O₃(0001) heterojunctions.

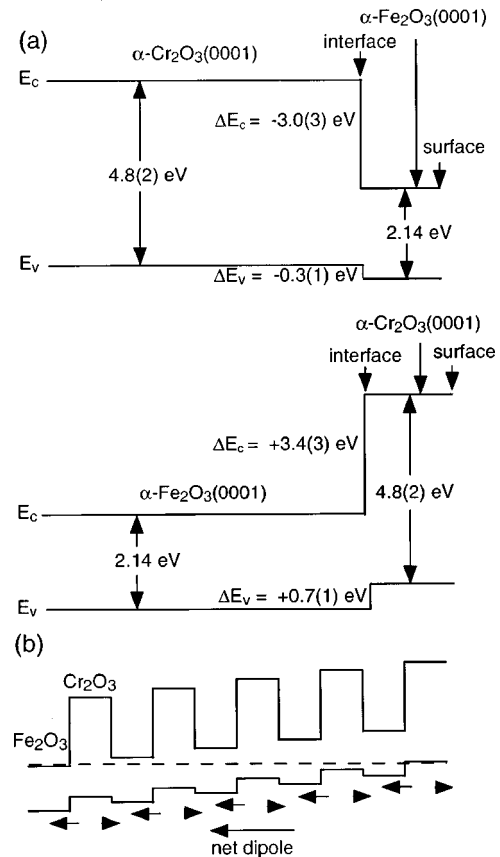


FIG. 8. Energy-level diagrams showing (a) the noncommutative band offsets for α -Fe₂O₃(0001)/ α -Cr₂O₃(0001) and α -Cr₂O₃(0001)/ α -Fe₂O₃(0001) heterojunctions, and (b) the potential gradient that develops over several superlattice periods as a result of the noncommutative band offsets.

epitaxial α -Cr₂O₃/ α -Fe₂O₃/.../ α -Al₂O₃(0001) by high-resolution electron-energy-loss spectroscopy. However, the energy-loss region within the Cr₂O₃ band gap contained features created by excitation of surface states, and an unambiguous determination of the band gap was not possible. Therefore, we have used the band gap of bulk Cr₂O₃ in Fig. 8(a).

IV. DISCUSSION

Based on what is known about traditional semiconductor band offsets, there are three possible physical causes for the noncommutative band offset seen here. The first of these is strain. Strain is known to have a large effect on some semiconductor band offsets. One example is Si/Ge. The lattice parameters of Si and Ge differ by 4%, and the critical thickness of epitaxial films of one on a substrate of the other is only a few monolayers. The valence-band offset of thin, pseudomorphic Si on Ge(001) is 0.74 eV whereas that for thin, pseudomorphic Ge on Si(001) is 0.17 eV.¹⁴ However, in this case, the strain configuration is different for the two interfaces; the thin epitaxial layer of Ge (Si) is in compression (tension) and the Si (Ge) substrate is unstrained. In contrast, Cr₂O₃(Fe₂O₃) is under tension (unstrained) for both Fe₂O₃/Cr₂O₃ and Cr₂O₃/Fe₂O₃ heterojunctions. In addition, band-offset measurements for Fe₂O₃/Cr₂O₃ heterojunctions in which both layers are relaxed are numerically the same as those for which the Cr₂O₃ layer is under tension and the Fe₂O₃ layer is relaxed. Therefore, we rule out strain as having any significant effect on the band offsets in this materials system

The second possible cause is quantum confinement. Limiting the thickness of an epitaxial layer can have the effect of altering the energy eigenvalues within the valence and conduction bands, thereby changing the band offsets.¹⁵ The change in eigenvalues depends on layer thickness. To test this possibility, we grew Fe₂O₃ and Cr₂O₃ overlayers of different thicknesses to see if the band offsets varied with thickness, and they did not. Therefore, quantum confinement is not a factor.

The third possible cause is a difference in interface dipole due to variations in the atomic configuration on either side of the interface. It has been shown that in theory, the exact atomic configuration at the interface can have a non-negligible effect on band offsets at Ge/GaAs and ZnSe/GaAs heterojunctions.¹ In addition, noncommutative band-offset behavior has been observed for lattice-matched Ga_{0.47}In_{0.53}As/InP(001), and was ascribed to the same cause.¹⁶ Fe is slightly more electronegative than Cr. Therefore, a dipole exists at each heterojunction interface, even if the interface is structurally perfect and completely abrupt. The dipole at a Fe₂O₃/Cr₂O₃ interface will be equal but opposite to that at a Cr₂O₃/Fe₂O₃ interface if there is no intermixing, or if the extent of intermixing is the same for the two interfaces, as illustrated in Fig. 9. Here, we show a thin epitaxial layer of Cr₂O₃ sandwiched between two layers of Fe₂O₃, and the associated interfaces, which are depicted as being perfectly abrupt on an atomic scale. The interface dipole moments are equal in magnitude but opposite in direction, as shown in Fig. 9. The dipoles will change in magnitude but in the same way, leading to a net cancellation, if

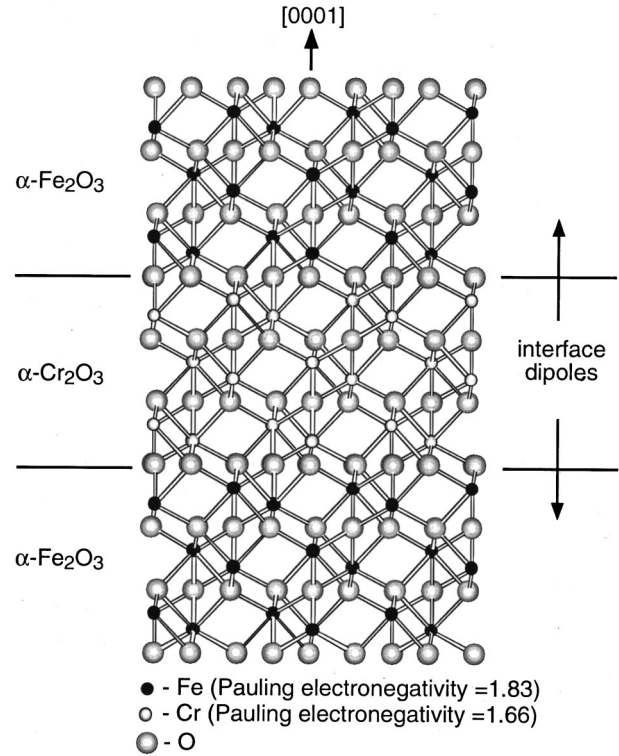


FIG. 9. Schematic structural diagram of an atomically abrupt α -Fe₂O₃/ α -Cr₂O₃/ α -Fe₂O₃(0001) layered system, showing the equal but opposite dipole moments that develop at each interface due to the different electronegativities of Cr and Fe.

intermixing occurs to the same extent at each interface. However, a nonzero net dipole will be established for each full period of the superlattice if the extents of intermixing are different at the two interfaces. This effect is shown schematically in Fig. 8(b). Detecting slight differences in intermixing between the two interfaces is exceedingly difficult. Nevertheless, we are currently designing experiments to do so. One technique that may yield definitive answers is TEM lattice imaging based on inelastically scattered electrons that have excited core-level transitions in Cr and Fe.¹⁷ By setting the energy-loss spectrometer at an energy window covering the *K* edge of Cr with a Gatan energy filter system, regions of the interfacial region that are rich in Cr will be highlighted. Likewise, for Fe, when the energy window covers the Fe *K*-edge loss feature. Accordingly, with a spatial resolution of ~ 1 nm, this measurement may allow the extent of intermixing to be determined on each side of the two interfaces. Another technique that may be useful is multi-atom resonant photoemission (MARPE).¹⁸ Interatomic resonant photoemission involving Fe and Cr might allow the extent of interfacial intermixing to be determined for specimens consisting of thin films of Cr₂O₃ on Fe₂O₃. Measuring the resonant enhancement of Cr *2p* photoemission as the Fe *2p*-*3d* transition is excited should in principle yield information on the spatial distribution outdiffused Fe in the Cr₂O₃ layer. The characteristic maximum sensing length of MARPE has been determined to be ~ 20 Å in Fe/Cr metallic alloys.¹⁹ Comparison of MARPE spectra of Cr₂O₃/Fe₂O₃ interfaces with those of well-defined Cr_{*x*}Fe_{2-*x*}O₃ reference films should allow the extent of outdiffusion of Fe into Cr₂O₃ to be determined.

A significant implication of the noncommutative band-

offset behavior noted above is that a potential gradient accompanying the net dipole would be established in superlattices of these materials. This situation is depicted schematically in Fig. 8(b). The potential gradient would ultimately be self-limiting over approximately five superlattice periods as the valence-band maximum at one end of the superlattice structure becomes higher in energy than the conduction-band minimum at the other end. At this point, carriers would flow and establish a gradient in the direction opposite to that created by the noncommutative band offsets. However, photoexcitation of electron-hole pairs anywhere in the structure would result in two kinds of carrier separation. First, the type-II band offset that exists would naturally drive electrons and holes to opposite ends of the structure. Second, the gradient that develops over several superlattice periods would drive electrons (holes) toward the low-(high-) electron-energy end of the structure. The efficiency with which this process occurs would depend on electron and hole mobilities and layer thicknesses, particularly for the Cr₂O₃ layers, at which the larger of the two potential barriers exists. Unfortunately, the insulating nature of these materials made it necessary to use an electron flood gun to neutralize the photoemission-induced surface charge, so it was not possible to track the absolute position of the core levels and, therefore, the valence-band maximum relative to the Fermi level, as different periods of the superlattices were grown. However, experiments are planned in which thin epitaxial films of Cr₂O₃ and Fe₂O₃ will be grown on Pt(111) so the valence-band energy relative to an absolute Fermi level can be tracked over at least a few superlattice periods. The in-plane

lattice parameter of Pt(111) is the same as that of α -Al₂O₃(0001), and high-quality films of Pt have been grown by MBE on α -Al₂O₃(0001).²⁰

V. CONCLUSIONS

In summary, MBE-grown α -Fe₂O₃(0001)/ α -Cr₂O₃(0001) superlattices, in which the Cr₂O₃ layers are in lateral tension by \sim 2% and the Fe₂O₃ layers are unstrained, exhibit unusual noncommutative band-offset behavior. This noncommutativity is in all likelihood caused by a growth-order-dependent interface dipole. Furthermore, the noncommutativity produces a potential gradient over several periods of the superlattice that may be useful for enhanced effectiveness in spatially separating electrons and holes.

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